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B4 G1  
11. (Amended) A method for producing a thin film-structure as defined in claim 10, wherein a magnetic layer made of a magnetic material is formed nearby the thin film, an opposite electrode being formed opposing to the magnetic layer, and the thin film is deformed by the magnetic external force generated between the magnetic layer and the opposite electrode.

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18. (Amended) A method for producing a thin film-structure as defined in claim 15, wherein the subsidiary layer is a mixed layer made of the material of the substrate and the amorphous material of the thin film.

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22. (Amended) A method for producing a thin film-structure as defined in claim 19, wherein the subsidiary layer is a mixed layer made of the material of the substrate and the amorphous material of the thin film.

# REMARKS

Claims 3-22 are pending with claims 1 and 2 being withdrawn from consideration by a Restriction Requirement. By this Amendment, the Abstract, specification and claims 3, 11, 18 and 22 are amended editorially and not for purposes of patentability under 35 U.S.C. §§101, 102, 103 and 112. It is respectfully submitted that no new matter is introduced by these amendments. Reconsideration of claims 3-22 in view of the foregoing amendments and the following remarks is respectfully requested.

## I. FORMAL MATTERS

A. The Office Action makes various objections to the Abstract and specification due to minor informalities. It is respectfully submitted that the foregoing amendments overcome these objections. Reconsideration of the objections in view of the amendments is respectfully requested.